Method and device for determining a deformation of a disc-shaped workpiece, particularly a mould wafer

Abstract

The present invention relates to a method and a device for determining a deformation of a disc-shaped workpiece, in particular a mould wafer. The device comprises a rotatable, height and laterally adjustable mounting unit (5, 5a, 15a-c; 5, 5a, 15d) for mounting an inner region (IB) of the disc-shaped workpiece (3); a determination unit (25) for determining eccentricity (δ) of a centre axis (M') of the disc-shaped workpiece (3) from a centre axis (M) of the mounting unit (5, 5a, 15a-c; 5, 5a, 15d) and for generating a suitable adjustment signal for the mounting unit (5, 5a, 15a-c; 5, 5a, 15d); a deposit unit (3a, 3b, 3c) for depositing the disc-shaped workpiece (3) during a process of lateral adjustment of the mounting unit (5, 5a, 15a-c; 5, 5a, 15d); and a fixed-height detector unit (50) for measuring a deviation (WR) of a plurality of measuring points (P1-P8), respectively, in a non-mounted outer region (AB) of the disc-shaped workpiece (3) from a predetermined height position (Z0) corresponding to the deformation by rotating the mounting unit (5, 5a, 15a-c; 5, 5a, 15d) or the detector unit (50) at a predetermined height position (Z0) of the mounting unit (5, 5a, 15a-c; 5, 5a, 15d).

(Fig. 1d)